

C-RW Series

Wafer Demounting & Cleaning Machine

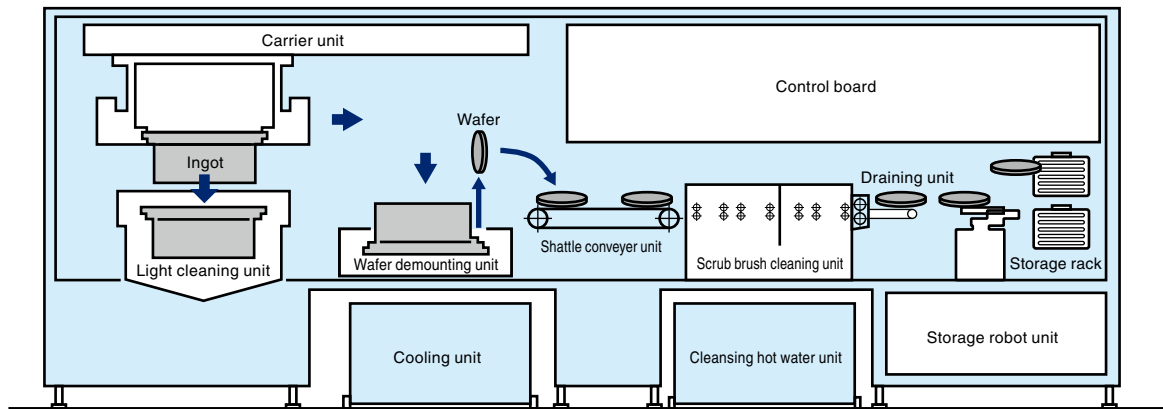
This multifunction wafer demounting and cleaning machine automatically conducts processes from light cleaning, wafer demounting and scrub cleaning of ingots sliced by wire saw to storage into cassettes.

- Designed to be compatible with gluing plates of all wire saw makers
Sliced ingots can be transferred by ingot lifters built specifically for wire saws
- Handles from water-based slurry to oil-based slurry, and cleaning solutions can be used and recycled through filters
- High throughput
- Makes low running costs possible



TOKYO SEIMITSU CO., LTD.

C-RW-345/C-RW-245



Light cleaning unit



Wafer demounting unit



Conveyor unit



Scrub brush cleaning unit



Cassette storage unit

Basic Specifications

Dimensions,Weight		*Height of indicator light
C-RW-245	5100(W) x 1450(D) x 2200(H) / 2800*mm, 5000kg	
C-RW-345	7100(W) x 1650(D) x 2400(H) / 3000*mm, 7000kg	
Applicable workpieces		
Ingot slice size	C-RW-245 : 8"(203mm), L(max) = 450mm C-RW-345 : 12"(304mm), L(max) = 450mm	
Multi-slicing capabilities	2 ingots	
Assorted materials	SUS304	
Housing frame material	Aluminum extrusion material	
Utility		
Cleaning solution	Water for industrial use or Clean-thru : KS-1000	
Air supply	At least 0.5MPa	
Power supply	200 VAC	
Exhaust ventilation	VP200	
Drain and exhaust port	50A	
Automation		
Host computer signals	SECS-1/2compliant, HSMS or RS232C connection possible	
Signal tower	3-color indicator	

Structural Specifications

Slide ingot carrier unit		
Slide unit & hand unit	Chuck with vertical 180° inversion mechanism	
Light cleaning unit and light cleaning lifter	Oscillating control on a light cleaning lifter	
Light cleaning (sliced cleaning)		
Structure	Chamber structure	
Cleaning	Splay nozzle showering Oscillating control and shower cleaning	
Wafer demounting		
Structure	Demounting tank + Wafering unit + Lot partition	
Demounting	Demounting tank max. temperature : 95°C	
Conveyor unit		
Structure	Shuttle conveyer	
Carrier	Max.speed : 80mm/sec	
Scrub cleaning unit		
Structure	Cleaning tank (Brush cleaning,rinse tank) + drying	
Cleaning	Front and back reversble brush + Cleaning water nozzle	
Supply unit/Storage unit		
Structure	Wafer carrier robot + carrier set	
Storage carrier	Cassette carrier type(4C/8C/12C:25cassettes per carrier)	

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